

Ion Beam Etch Rates And Sputter Yields

Argon at 500 eV
Normal Incidence
1mA/cm² Beam Current Density

H 1 13.595 1.008	Li 3 5.39 75.619 122.419 6.939	Be 4 9.32 18.206 153.85 130 0.43 9.012 303	Na 11 5.138 47.29 71.715 22.990	Mg 12 7.644 15.031 80.14 225 24.312	K 19 4.339 31.81 46 39.102	Ca 20 6.111 11.868 51.21 40.08	Sc 21 6.54 12.8 24.75 44.956	Ti 22 6.82 13.57 27.47 330 0.50 47.90 655	V 23 6.74 14.65 29.31 310 0.60 50.942 450	Cr 24 6.764 16.49 29.31 30.95 530 1.2 51.996 459	Mn 25 7.432 15.636 29.31 30.643 350 0.90 54.938 459	Fe 26 7.87 16.18 30.643 33.69 350 0.90 55.847 441	Co 27 7.86 17.05 33.49 450 1.3 58.933 412	Ni 28 7.633 18.15 35.16 530 1.3 58.71 410	Cu 29 7.724 20.29 36.83 880 2.0 63.544 441	Zn 30 9.391 17.96 39.7 65.373	Al 13 5.984 18.823 28.44 640 26.982 621	Si 14 8.149 16.34 33.488 370 0.5 28.086 750	B 5 8.296 25.149 37.92 10.811 290	C 6 11.256 24.376 47.871 110 0.36 12.011 393	N 7 14.53 29.593 47.426 14.007	O 8 13.614 35.108 54.886 15.999	F 9 17.418 34.98 62.646 18.998	Ne 10 21.559 41.07 63.5 20.183	Ar 18 15.755 27.62 40.9 39.948	Cl 17 13.01 23.8 35 39.9 35.453	Br 35 11.84 21.6 35.9 79.909	Kr 36 13.996 24.56 36.9 83.80	As 33 9.81 18.63 34.21 920 74.922	Se 34 9.75 21.5 32 78.966	Ge 32 7.88 15.93 34.21 920 72.59 848	Sn 50 7.342 14.628 30.49 1200 1.2 118.69 1010	Sb 51 8.639 16.5 25.3 1200 121.75 1131	Te 52 9.01 18.6 31 1271	I 53 10.454 19.13 126.904	Xe 54 12.127 21.2 31.3 131.30	Cs 55 3.893 25.1 35 132.905	Ba 56 5.21 10.001 35.5 137.34	La 57 5.61 11.43 19.17 138.91	Hf 72 7 14.9 23.2 660 0.79 173.49 833	Ta 73 7.88 16.2 420 0.62 180.948 675	W 74 7.98 17.7 340 0.60 183.85 592	Re 75 7.87 16.6 520 0.95 186.1 551	Os 76 8.5 17 500 0.96 190.2 524	Ir 77 9 590 1.1 192.2 535	Rh 45 7.46 18.07 31.05 720 1.4 102.95 516	Pd 46 8.33 19.42 32.92 1100 2.0 106.4 550	Ag 47 7.574 21.48 34.82 1800 2.8 107.870 639	Cd 48 8.991 16.904 37.47 112.40	In 49 5.785 18.86 28.03 114.82	Ga 31 5 20.57 30.7 69.72	Ge 32 7.88 15.93 34.21 920 72.59 848	As 33 9.81 18.63 34.21 920 74.922	Se 34 9.75 21.5 32 78.966	Br 35 11.84 21.6 35.9 79.909	Kr 36 13.996 24.56 36.9 83.80	Ru 44 7.364 16.76 28.46 610 1.2 101.07 506	Rh 45 7.46 18.07 31.05 720 1.4 102.95 516	Pd 46 8.33 19.42 32.92 1100 2.0 106.4 550	Ag 47 7.574 21.48 34.82 1800 2.8 107.870 639	Cd 48 8.991 16.904 37.47 112.40	In 49 5.785 18.86 28.03 114.82	Sn 50 7.342 14.628 30.49 1200 1.2 118.69 1010	Sb 51 8.639 16.5 25.3 1200 121.75 1131	Te 52 9.01 18.6 31 1271	I 53 10.454 19.13 126.904	Xe 54 12.127 21.2 31.3 131.30	Ce 58 5.6 12.3 20 140.12	Pr 59 5.46 140.907	Nd 60 5.51 144.24	Pm 61 (147)	Sm 62 5.6 11.2 1100 0.87 150.35 1244	Eu 63 5.67 11.24 151.96	Gd 64 6.16 12 1100 0.90 157.25 1238	Tb 65 5.98 158.924	Dy 66 6.8 1100 162.50 1182	Ho 67 164.930	Er 68 6.08 1000 0.85 167.26	Tm 69 5.81 168.934	Yb 70 6.2 12.10 173.04	Lu 71 0.0 14.7 174.97	Th 90 6.95 810 0.66 232.038 1231	Pa 91 (231)	U 92 6.08 730 0.94 238.03 781	Np 93 (237)	Pu 94 5.1 (242)	Am 95 (243)	Cm 96 (247)	Bk 97 (247)	Cf 98 (249)	Es 99 (254)	Fm 100 (257)	Md 101 (258)	No 102 (259)	Lr 103 (260)
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Au
 ■ ATOMIC NO.
 ■ IONIZATION POTENTIAL (volts)
 ■ ION BEAM ETCH RATE (Å/min)
 ■ SPUTTER YIELD (atoms/ion)
 ■ ATOMIC WEIGHT
 ■ Y-FACTOR

KEY